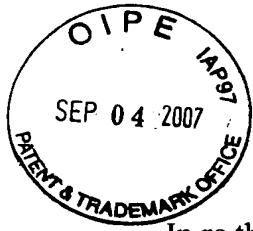


**PATENT APPLICATION**



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Koichi KANAYA et al.

Group Art Unit: 1709

Application No.: 10/565,653

Examiner: K. CHEN

Filed: January 24, 2006

Docket No.: 126247

For: VAPOR DEPOSITION APPARATUS AND VAPOR DEPOSITION METHOD

**AMENDMENT UNDER 37 C.F.R. §1.111**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the May 2, 2007 Office Action, the period for reply being extended by the Petition for Extension of Time filed herewith, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**